



10/19/00

IFW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re patent of :

Shoriki NARITA et al. :

Patent No. 6,818,975 :

Issued November 16, 2004 :

BUMP FORMING APPARATUS FOR :  
CHARGE APPEARANCE SEMICONDUCTOR  
SUBSTRATE, CHARGE REMOVAL METHOD  
FOR CHARGE APPEARANCE SEMICONDUCTOR  
SUBSTRATE, CHARGE REMOVING UNIT FOR  
CHARGE APPEARANCE SEMICONDUCTOR  
SUBSTRATE, AND CHARGE APPEARANCE  
SEMICONDUCTOR SUBSTRATE

THE COMMISSIONER IS AUTHORIZED  
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ACCOUNT NO. 23-0975

SUBMISSION OF REFERENCES

Commissioner for Patents  
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Alexandria, VA 22313-1450

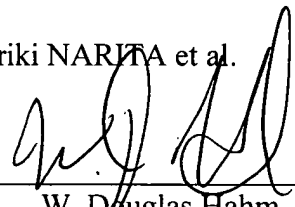
Sir:

Applicants hereby request that the copy of the attached reference JP 6-232132 be placed in the file for the above-referenced application. The reference was cited in a corresponding Japanese application on September 7, 2004.

Respectfully submitted,

Shoriki NARITA et al.

By

  
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